

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Application Serial No. 10/733,201
Filing Date December 9, 2003
Confirmation No. 5994
Inventor Garo J. Derderian et al.
Assignee Micron Technology, Inc.
Group Art Unit 1762
Examiner Kelly M. Stouffer
Attorney's Docket No. MI22-2402
Customer No. 021567
Title: Atomic Layer Deposition Method of Depositing an Oxide on a Substrate

RESPONSE TO SEPTEMBER 28, 2007 FINAL OFFICE ACTION
PRELIMINARY AMENDMENT TO ACCOMPANY RCE FILING

To: Mail Stop RCE
Commissioner for Patents
P. O. Box 1450
Alexandria, VA 22313-1450

From: Mark S. Matkin (Tel. 509-624-4276; Fax 509-838-3424)
Wells St. John P.S.
601 West First Avenue, Suite 1300
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Responsive to the Final Office Action dated September 28, 2007, Applicant
amends and remarks as follows:

AMENDMENTS